

Hei Wong

List of Publications by Year in descending order

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159
papers

2,574
citations

218677

26
h-index

233421

45
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161
all docs

161
docs citations

161
times ranked

2225
citing authors

#	ARTICLE	IF	CITATIONS
1	On the scaling issues and high- κ replacement of ultrathin gate dielectrics for nanoscale MOS transistors. <i>Microelectronic Engineering</i> , 2006, 83, 1867-1904.	2.4	325
2	Low-frequency noise study in electron devices: review and update. <i>Microelectronics Reliability</i> , 2003, 43, 585-599.	1.7	93
3	Atomic and electronic structure of amorphous and crystalline hafnium oxide: X-ray photoelectron spectroscopy and density functional calculations. <i>Journal of Applied Physics</i> , 2007, 101, 053704.	2.5	84
4	Excess silicon at the silicon nitride/thermal oxide interface in oxide/nitride/oxide structures. <i>Journal of Applied Physics</i> , 1999, 86, 3234-3240.	2.5	83
5	Study of the electronic trap distribution at the SiO ₂ /Si interface utilizing the low-frequency noise measurement. <i>IEEE Transactions on Electron Devices</i> , 1990, 37, 1743-1749.	3.0	81
6	Defects in silicon oxynitride gate dielectric films. <i>Microelectronics Reliability</i> , 2002, 42, 597-605.	1.7	81
7	XPS Study of the Thermal Instability of HfO ₂ Prepared by Hf Sputtering in Oxygen with RTA. <i>Journal of the Electrochemical Society</i> , 2003, 150, F200.	2.9	78
8	Short-range order in non-stoichiometric amorphous silicon oxynitride and silicon-rich nitride. <i>Journal of Non-Crystalline Solids</i> , 2002, 297, 96-101.	3.1	67
9	X-ray photoelectron spectroscopy study of high- κ CeO ₂ /La ₂ O ₃ stacked dielectrics. <i>AIP Advances</i> , 2014, 4, .	1.3	67
10	Interface bonding structure of hafnium oxide prepared by direct sputtering of hafnium in oxygen. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 2004, 22, 1094.	1.6	58
11	The road to miniaturization. <i>Physics World</i> , 2005, 18, 40-44.	0.0	57
12	Preparation of Thin Dielectric Film for Nonvolatile Memory by Thermal Oxidation of Si-Rich LPCVD Nitride. <i>Journal of the Electrochemical Society</i> , 2001, 148, G275.	2.9	51
13	Recent developments in silicon optoelectronic devices. <i>Microelectronics Reliability</i> , 2002, 42, 317-326.	1.7	51
14	Luminescence of intrinsic and extrinsic defects in hafnium oxide films. <i>Physical Review B</i> , 2007, 76, .	3.2	50
15	Silicon dots/clusters in silicon nitride: photoluminescence and electron spin resonance. <i>Thin Solid Films</i> , 1999, 353, 20-24.	1.8	49
16	A physically-based MOS transistor avalanche breakdown model. <i>IEEE Transactions on Electron Devices</i> , 1995, 42, 2197-2202.	3.0	44
17	On the scaling of subnanometer EOT gate dielectrics for ultimate nano CMOS technology. <i>Microelectronic Engineering</i> , 2015, 138, 57-76.	2.4	42
18	Trapping characteristics of lanthanum oxide gate dielectric film explored from temperature dependent current-voltage and capacitance-voltage measurements. <i>Solid-State Electronics</i> , 2007, 51, 475-480.	1.4	39

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19	Material properties of interfacial silicate layer and its influence on the electrical characteristics of MOS devices using hafnia as the gate dielectric. <i>Thin Solid Films</i> , 2006, 504, 192-196.	1.8	33
20	Silicon integrated photonics begins to revolutionize. <i>Microelectronics Reliability</i> , 2007, 47, 1-10.	1.7	33
21	Silicon oxynitride prepared by chemical vapor deposition as optical waveguide materials. <i>Journal of Crystal Growth</i> , 2006, 288, 171-175.	1.5	31
22	XPS study on the effects of thermal annealing on CeO ₂ /La ₂ O ₃ stacked gate dielectrics. <i>Thin Solid Films</i> , 2016, 600, 30-35.	1.8	31
23	Excess silicon at the Si ₃ N ₄ /SiO ₂ interface. <i>Applied Physics Letters</i> , 1998, 72, 462-464.	3.3	30
24	Interface structure of ultrathin oxide prepared by N ₂ /O oxidation. <i>IEEE Transactions on Electron Devices</i> , 2003, 50, 1941-1945.	3.0	30
25	Atomic and electronic structures of amorphous ZrO ₂ and HfO ₂ films. <i>Microelectronic Engineering</i> , 2005, 81, 524-529.	2.4	30
26	Analytical model of drain current of cylindrical surrounding gate p-n-i-n TFET. <i>Solid-State Electronics</i> , 2015, 111, 171-179.	1.4	30
27	Valence band offset at silicon/silicon nitride and silicon nitride/silicon oxide interfaces. <i>Thin Solid Films</i> , 2003, 437, 135-139.	1.8	29
28	Drain breakdown in submicron MOSFETs: a review. <i>Microelectronics Reliability</i> , 2000, 40, 3-15.	1.7	28
29	Bonding and band offset in N ₂ O-grown oxynitride. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 2003, 21, 241.	1.6	27
30	The interfaces of lanthanum oxide-based subnanometer EOT gate dielectrics. <i>Nanoscale Research Letters</i> , 2014, 9, 472.	5.7	26
31	Study of Excess Silicon at Si ₃ N ₄ /Thermal SiO ₂ Interface Using EELS and Ellipsometric Measurements. <i>Journal of the Electrochemical Society</i> , 1999, 146, 780-785.	2.9	24
32	Oxynitride gate dielectric prepared by thermal oxidation of low-pressure chemical vapor deposition silicon-rich silicon nitride. <i>Microelectronics Reliability</i> , 2003, 43, 611-616.	1.7	24
33	Electrical characterization of the hafnium oxide prepared by direct sputtering of Hf in oxygen with rapid thermal annealing. <i>Microelectronics Reliability</i> , 2003, 43, 1289-1293.	1.7	24
34	CHALLENGES FOR FUTURE SEMICONDUCTOR MANUFACTURING. <i>International Journal of High Speed Electronics and Systems</i> , 2006, 16, 43-81.	0.7	24
35	Temperature dependences of threshold voltage and drain-induced barrier lowering in 60nm gate length MOS transistors. <i>Microelectronics Reliability</i> , 2014, 54, 1109-1114.	1.7	24
36	Dynamic Analysis of Two-Phase Switched-Capacitor DC-DC Converters. <i>IEEE Transactions on Power Electronics</i> , 2014, 29, 302-317.	7.9	21

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37	Dielectric breakdown characteristics and interface trapping of hafnium oxide films. <i>Microelectronics Journal</i> , 2005, 36, 29-33.	2.0	20
38	Electrical characteristics of high- ϵ^{Hf} dielectric film grown by direct sputtering method. <i>Solid-State Electronics</i> , 2006, 50, 237-240.	1.4	20
39	Modeling of the parasitic transistor-induced drain breakdown in MOSFETs. <i>IEEE Transactions on Electron Devices</i> , 1996, 43, 2190-2196.	3.0	19
40	Effects of aluminum doping on lanthanum oxide gate dielectric films. <i>Vacuum</i> , 2012, 86, 929-932.	3.5	19
41	Modeling and characterization of direct-tunneling current in dual-layer ultrathin-gate dielectric films. <i>Journal of Vacuum Science & Technology B</i> , 2006, 24, 1785.	1.3	18
42	Accurate Ellipsometric Measurement of Refractive Index and Thickness of Ultrathin Oxide Film. <i>Journal of the Electrochemical Society</i> , 2006, 153, F277.	2.9	18
43	Effects and mechanisms of nitrogen incorporation into hafnium oxide by plasma immersion implantation. <i>Journal of Vacuum Science & Technology B</i> , 2007, 25, 1853.	1.3	18
44	Current transport and high-field reliability of aluminum/hafnium oxide/silicon structure. <i>Thin Solid Films</i> , 2006, 504, 312-316.	1.8	17
45	Atomic and Electronic Structures of Traps in Silicon Oxide and Silicon Oxynitride. <i>Critical Reviews in Solid State and Materials Sciences</i> , 2011, 36, 129-147.	12.3	17
46	Electrically tunable film bulk acoustic resonator based on Au/ZnO/Al structure. <i>Applied Physics Letters</i> , 2013, 103, .	3.3	16
47	High-k Gate Dielectrics. <i>Electrochemical Society Interface</i> , 2005, 14, 30-34.	0.4	16
48	Onefold coordinated oxygen atom: an electron trap in the silicon oxide. <i>Microelectronics Reliability</i> , 2003, 43, 665-669.	1.7	15
49	Quasi-analytical model of ballistic cylindrical surrounding gate nanowire MOSFET. <i>Microelectronic Engineering</i> , 2015, 138, 111-117.	2.4	15
50	Review on peculiar issues of field emission in vacuum nanoelectronic devices. <i>Solid-State Electronics</i> , 2017, 138, 3-15.	1.4	14
51	Current conduction and stability of CeO ₂ /La ₂ O ₃ stacked gate dielectric. <i>Applied Physics Letters</i> , 2012, 101, 233507.	3.3	13
52	Modeling of a EEPROM device based on silicon quantum dots embedded in high-k dielectrics. <i>Microelectronic Engineering</i> , 2005, 81, 530-534.	2.4	12
53	Bonding Structure of Silicon Oxynitride Grown by Plasma-Enhanced Chemical Vapor Deposition. <i>Japanese Journal of Applied Physics</i> , 2007, 46, 3202-3205.	1.5	12
54	Effects of aluminum incorporation on hafnium oxide film using plasma immersion ion implantation. <i>Microelectronics Reliability</i> , 2008, 48, 1765-1768.	1.7	12

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55	An overview of charge pumping circuits for flash memory applications. , 2011, , .		12
56	The variation of the leakage current characteristics of W/Ta ₂ O ₅ /W MIM capacitors with the thickness of the bottom W electrode. Microelectronics Reliability, 2016, 61, 95-98.	1.7	12
57	Short-range order and luminescence in amorphous silicon oxynitride. The Philosophical Magazine: Physics of Condensed Matter B, Statistical Mechanics, Electronic, Optical and Magnetic Properties, 2000, 80, 1857-1868.	0.6	11
58	Nitrogen Incorporation into Hafnium Oxide Films by Plasma Immersion Ion Implantation. Japanese Journal of Applied Physics, 2007, 46, 3234-3238.	1.5	11
59	Off-state drain breakdown mechanisms of VDMOS with anti-JFET implantation. Microelectronics Reliability, 2011, 51, 2064-2068.	1.7	11
60	On the design of power- and area-efficient Dickson charge pump circuits. Analog Integrated Circuits and Signal Processing, 2014, 78, 373-389.	1.4	11
61	Thermal annealing, interface reaction, and lanthanum-based sub-nanometer EOT gate dielectrics. Vacuum, 2015, 118, 2-7.	3.5	11
62	Substrate current, gate current and lifetime prediction of deep-submicron nMOS devices. Solid-State Electronics, 2005, 49, 505-511.	1.4	10
63	Single band electronic conduction in hafnium oxide prepared by atomic layer deposition. Microelectronics Reliability, 2007, 47, 36-40.	1.7	10
64	Subthreshold Characteristics of MOS Transistors With $\text{hbox{CeO}}_{2}/\text{hbox{La}}_{2}\text{hbox{O}}_{3}$ Stacked Gate Dielectric. IEEE Electron Device Letters, 2011, 32, 1002-1004.	3.9	10
65	Electronic structures of silicon nitride revealed by tight binding calculations. Journal of Non-Crystalline Solids, 2008, 354, 1531-1536.	3.1	9
66	Subthreshold parameters of radio-frequency multi-finger nanometer MOS transistors. Microelectronics Reliability, 2009, 49, 387-391.	1.7	9
67	On the Vertically Stacked Gate-All-Around Nanosheet and Nanowire Transistor Scaling beyond the 5 nm Technology Node. Nanomaterials, 2022, 12, 1739.	4.1	9
68	A novel approach for fabricating light-emitting porous polysilicon films. Microelectronics Reliability, 2002, 42, 929-933.	1.7	8
69	Photoluminescence of Silicon Nanocrystals Embedded in Silicon Oxide. Journal of Nanoscience and Nanotechnology, 2009, 9, 1272-1276.	0.9	8
70	Transient Sensitivity of Sectorial Split-Drain Magnetic Field-Effect Transistor. IEEE Transactions on Magnetics, 2013, 49, 4048-4051.	2.1	8
71	Parasitic capacitance effect on the performance of two-â€phase switched-â€capacitor DC-â€DC converters. IET Power Electronics, 2015, 8, 1195-1208.	2.1	8
72	High-efficiency light-emitting device based on silicon nanostructures and tunneling carrier injection. Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena, 2005, 23, 2449.	1.6	7

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73	High-Performance Resistorless Sub-1V Bandgap Reference Circuit Based on Piecewise Compensation Technique. , 2007, , .		7
74	Design strategy for 2-phase switched capacitor charge pump. , 2008, , .		7
75	Generating sub-1V reference voltages from a resistorless CMOS bandgap reference circuit by using a piecewise curvature temperature compensation technique. Microelectronics Reliability, 2010, 50, 1054-1061.	1.7	7
76	An LED driver with thermal control function. , 2014, , .		7
77	AFM study on the surface morphologies of TiN films prepared by magnetron sputtering and Al ₂ O ₃ films prepared by atomic layer deposition. Vacuum, 2018, 153, 139-144.	3.5	7
78	Quantum charge transportation in metal-oxide-Si structures with ultrathin oxide. Journal of Vacuum Science & Technology B, 2006, 24, 38.	1.3	6
79	A dynamicâ€biasing 4Å— charge pump based on exponential topology. International Journal of Circuit Theory and Applications, 2015, 43, 401-414.	2.0	6
80	A high-efficiency full-wave CMOS rectifying charge pump for RF energy harvesting applications. Microelectronics Journal, 2015, 46, 1447-1452.	2.0	6
81	Electroluminescence of silicon nanoclusters excited by tunneling carrier injection. Journal of Vacuum Science & Technology B, 2008, 26, 813-820.	1.3	5
82	Design strategy for two-phase switched capacitor step-up charge pump. , 2009, , .		5
83	Wigner crystallization due to electrons localized at deep traps in two-dimensional amorphous dielectric. Applied Physics Letters, 2010, 96, 263510.	3.3	5
84	Thermal and voltage instabilities of hafnium oxide films prepared by sputtering technique. Microelectronics Reliability, 2013, 53, 1863-1867.	1.7	5
85	Split-Drain Magnetic Field-Effect Transistor Channel Charge Trapping and Stress Induced Sensitivity Deterioration. IEEE Transactions on Magnetics, 2014, 50, 1-4.	2.1	5
86	Snapback breakdown ESD device based on zener diodes on silicon-on-insulator technology. Microelectronics Reliability, 2014, 54, 1163-1168.	1.7	5
87	Effects of thermal annealing on the charge localization characteristics of HfO ₂ /Au/HfO ₂ stack. Microelectronics Reliability, 2016, 61, 78-81.	1.7	5
88	Geometry and temperature effects on the threshold voltage characteristics of silicon nanowire MOS transistors. Solid-State Electronics, 2017, 138, 35-39.	1.4	5
89	High-Speed Discrete Gaussian Sampler With Heterodyne Chaotic Laser Inputs. IEEE Transactions on Circuits and Systems II: Express Briefs, 2018, 65, 794-798.	3.0	5
90	Characteristic Variabilities of Subnanometer EOT La ₂ O ₃ Gate Dielectric Film of Nano CMOS Devices. Nanomaterials, 2021, 11, 2118.	4.1	5

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91	Effects of silicon surface defects on the graphene/silicon Schottky characteristics. Results in Physics, 2021, 29, 104744.	4.1	5
92	Piece-wise linear approximation of MOS nonlinear junction capacitance in high-frequency class E amplifier design. , 0, , .		4
93	Topology, analysis, and CMOS implementation of switched-capacitor DC-DC converters. Facta Universitatis - Series Electronics and Energetics, 2014, 27, 41-56.	0.9	4
94	Optimal design of high output power class E amplifier. , 0, , .		3
95	Silicon integrated photonics: potentials and promises. , 0, , .		3
96	Nanoscale MOS devices: device parameter fluctuations and low-frequency noise (Invited Paper). , 2005, , .		3
97	The Current Conduction Issues in High-k Gate Dielectrics. , 2007, , .		3
98	Effects of nitrogen incorporation into lanthana film by plasma immersion ion implantation. Solid-State Electronics, 2009, 53, 355-358.	1.4	3
99	A novel gate boosting circuit for 2-phase high voltage CMOS charge pump. , 2009, , .		3
100	Double edge-triggered half-static clock-gated D-type flip-flop. , 2010, , .		3
101	Advances in non-volatile memory technology. Microelectronics Reliability, 2012, 52, 611-612.	1.7	3
102	Modelling of maximum power efficiency of charge pump circuits. Electronics Letters, 2014, 50, 1233-1234.	1.0	3
103	Lanthana and its interface with silicon. , 2014, , .		3
104	Comparative study of resonant and sequential features in electron field emission from composite surfaces. Thin Solid Films, 2016, 608, 26-33.	1.8	3
105	Effects of thermal annealing on the interface between tungsten and CeO ₂ /La ₂ O ₃ stack gate dielectrics. Vacuum, 2017, 140, 7-13.	3.5	3
106	Analytical modeling on the drain current characteristics of gate-all-around TFET with the incorporation of short-channel effects. Solid-State Electronics, 2017, 138, 24-29.	1.4	3
107	Recent developments in silicon optoelectronic devices. , 0, , .		2
108	Dielectric breakdown characteristics and interface trapping of hafnium oxide films. , 0, , .		2

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109	On the Reliability Issues of RF CMOS Devices. , 2006, , .		2
110	Analysis of ESD discharge current distribution and area optimization of VDMOS gate protection structure. Microelectronics Reliability, 2010, 50, 622-626.	1.7	2
111	AN ENERGY EFFICIENT HALF-STATIC CLOCK-GATING D-TYPE FLIP-FLOP. Journal of Circuits, Systems and Computers, 2010, 19, 635-654.	1.5	2
112	Thermal stability of sectorial split-drain magnetic field-effect transistors. Microelectronics Reliability, 2014, 54, 1115-1118.	1.7	2
113	Low-voltage CMOS DC-DC converters for energy harvesting applications. , 2015, , .		2
114	Sensitivity distortion of split-drain MAGFET under alternating magnetic field. , 2015, , .		2
115	Tunneling-based charge percolation transport in a random network of semi-conductive nanoclusters embedded in a dielectric matrix. Thin Solid Films, 2015, 574, 84-92.	1.8	2
116	A low power CMOS magnetic field sensor consisting of a MAGFET and a pulse width modulated readout circuit. , 2017, , .		2
117	Compact Modeling and Short-Channel Effects of Nanowire MOS Transistors (Invited). , 2018, , .		2
118	Temperature dependent characteristics of graphene/silicon Schottky junction. International Journal of Nanotechnology, 2020, 17, 4.	0.2	2
119	A new approach to characterize and predict lifetime of deep-submicron nMOS devices. , 0, , .		1
120	Modeling of Low-Frequency Noise in Junction Field-Effect Transistor with Self-Aligned Planer Technology. , 0, , .		1
121	Effects of Ambient Temperature on the Electrical Characteristics of Thin La ₂ O ₃ /SiO ₂ Film Grown by E-Beam Evaporation. , 0, , .		1
122	Material and interface instabilities of high-κ; MOS gate dielectric films. , 2006, , .		1
123	Definition of curve fitting parameter to study tunneling and trapping of electrons in Si/ultra-thin SiO ₂ /metal structures. Microelectronics Reliability, 2006, 46, 1027-1034.	1.7	1
124	Silicon Integrated Photonics for Microelectronics Evolution. , 0, , .		1
125	Properties of high-dielectric constant complex materials based on transition and rare-earth metal oxides. , 2008, , .		1
126	A Wideband three-stage rail-to-rail power amplifier driving large capacitive load. , 2008, , .		1

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127	Background analysis of field-induced electron emission from nanometer-scale heterostructured emitters. <i>Journal of Vacuum Science & Technology B</i> , 2009, 27, 711-718.	1.3	1
128	Area efficient 2π switched capacitor charge pump. , 2009, , .		1
129	Probability Current and Antiresonances of Particle Tunneling Through Biased Heterostructures. <i>Journal of Nanoscience and Nanotechnology</i> , 2009, 9, 1237-1241.	0.9	1
130	A low-voltage charge pump with wide current driving capability. , 2010, , .		1
131	Modeling of terminal ring structures for high-voltage power MOSFETs. <i>Microelectronics Reliability</i> , 2012, 52, 1645-1650.	1.7	1
132	Effects of High-Temperature Treatment on the Reaction Between Sn-3%Ag-0.5%Cu Solder and Sputtered Ni-V Film on Ferrite Substrate. <i>Journal of Electronic Materials</i> , 2012, 41, 3145-3151.	2.2	1
133	Analytical Model of Subthreshold Drain Current Characteristics of Ballistic Silicon Nanowire Transistors. <i>Advances in Condensed Matter Physics</i> , 2015, 2015, 1-8.	1.1	1
134	Abnormal off-state current in multiple silicon nanowire MOS transistors. , 2015, , .		1
135	Analysis and design of CMOS full-wave rectifying charge pump for RF energy harvesting applications. , 2015, , .		1
136	On the scaling of lanthanum oxide gate dielectric film into the subnanometer EOT range. , 2016, , .		1
137	On the Issues of Subnanometer EOT Gate Dielectric Scaling. , 2019, , .		1
138	Effects of non-fatal electrostatic discharge on the threshold voltage degradation in nano CMOS devices. <i>Science China Information Sciences</i> , 2022, 65, 1.	4.3	1
139	Formation mechanism of light-emitting porous silicon prepared by reactive ions etching. , 0, , .		0
140	Photoluminescence of porous silicon and porous polysilicon films. , 0, , .		0
141	Charge trapping and stress-induced dielectric breakdown characteristics of HfO ₂ films. , 0, , .		0
142	Thermal stability and electronic structure of hafnium and zirconium oxide films for nanoscale MOS device applications. , 0, , .		0
143	A NEW APPROACH TO CHARACTERIZE AND PREDICT LIFETIME OF DEEP-SUBMICRON NMOS DEVICES. <i>International Journal of High Speed Electronics and Systems</i> , 2006, 16, 315-323.	0.7	0
144	Aluminium Incorporation in Lanthanum Oxide Films by using Plasma Immersion Ion Implantation. , 2007, , .		0

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145	Design and analysis of 600 V power MOSFET with multiple field limiting ring. , 2008, , .		0
146	Current mode track and hold circuit with 50MS/sec speed and 8-bit resolution. , 2008, , .		0
147	A low power temperature insensitive voltage supervisory circuit in metal gate technology. , 2009, , .		0
148	Quantum tunneling based percolating transport of electric charges in a network of conductive nanoclusters embedded in a dielectric matrix. , 2013, , .		0
149	A regulated charge pump with wide current driving capability for low-voltage applications. , 2014, , .		0
150	Observation of Substrate Silicon Incorporation into Thin Lanthanum Oxide Film during Rapid Thermal Annealing. Advanced Materials Research, 0, 1120-1121, 414-418.	0.3	0
151	On the compact modeling of double gate p-n-i-n tunneling field-effect transistors. , 2015, , .		0
152	Optimization of loss tangent and capacitor area of micro vacuum dielectric capacitors. , 2015, , .		0
153	XPS study on the effects of thermal annealing on CeO ₂ /La ₂ O ₃ stacked gate dielectrics. , 2015, , .		0
154	A study on split-drain MAGFET channel boundary charge trapping based on numerical simulation. , 2017, , .		0
155	On the RF energy harvesting based on CMOS technology. , 2018, , .		0
156	Compact modeling of sectorial split-drain magnetic field-effect transistors. Vacuum, 2019, 167, 68-72.	3.5	0
157	CMOS low power split-drain MAGFET based magnetic field strength sensor. Microelectronics Journal, 2020, 100, 104759.	2.0	0
158	A system-on-chip 1.5 GHz phase locked loop realized using 40 nm CMOS technology. Facta Universitatis - Series Electronics and Energetics, 2018, 31, 101-113.	0.9	0
159	High-K Gate Dielectrics. , 2019, , 105-140.		0